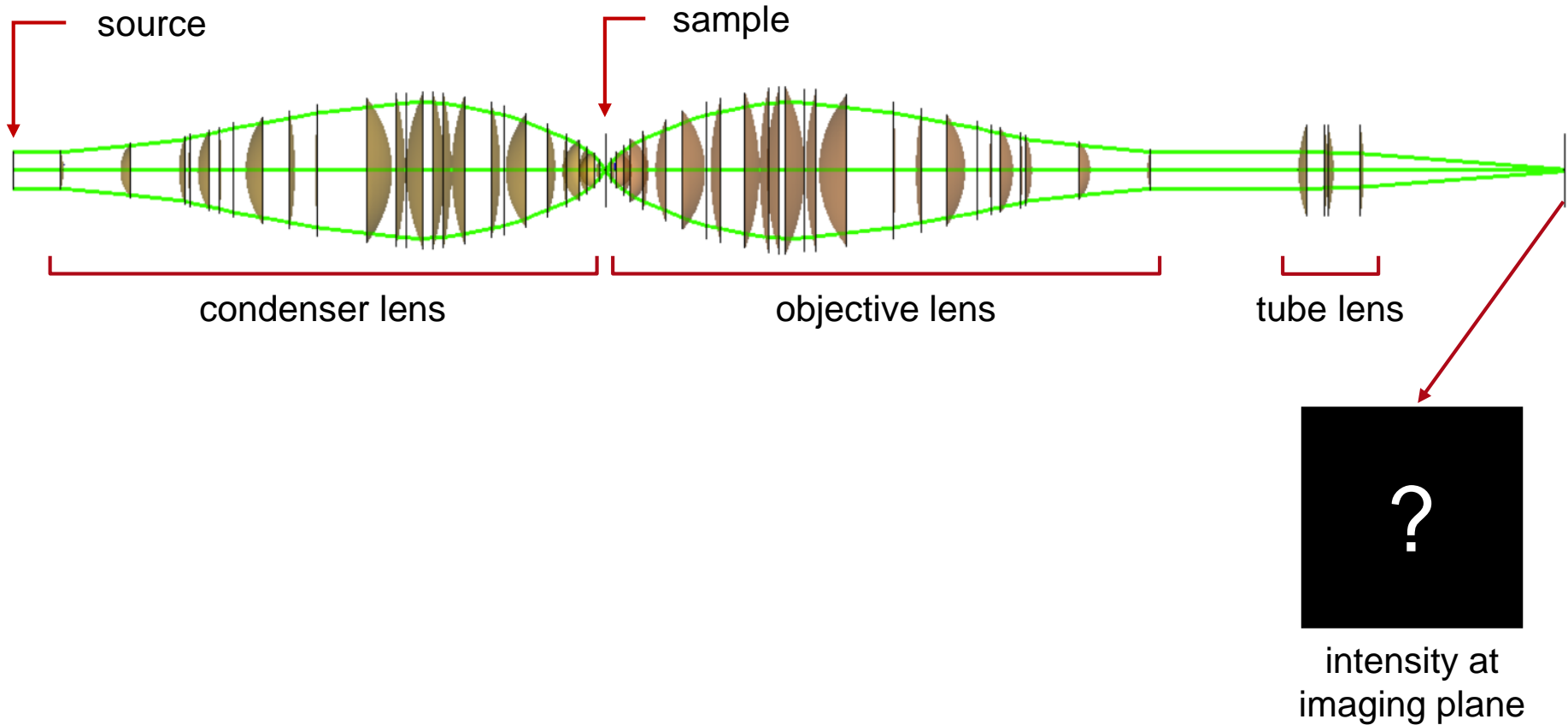


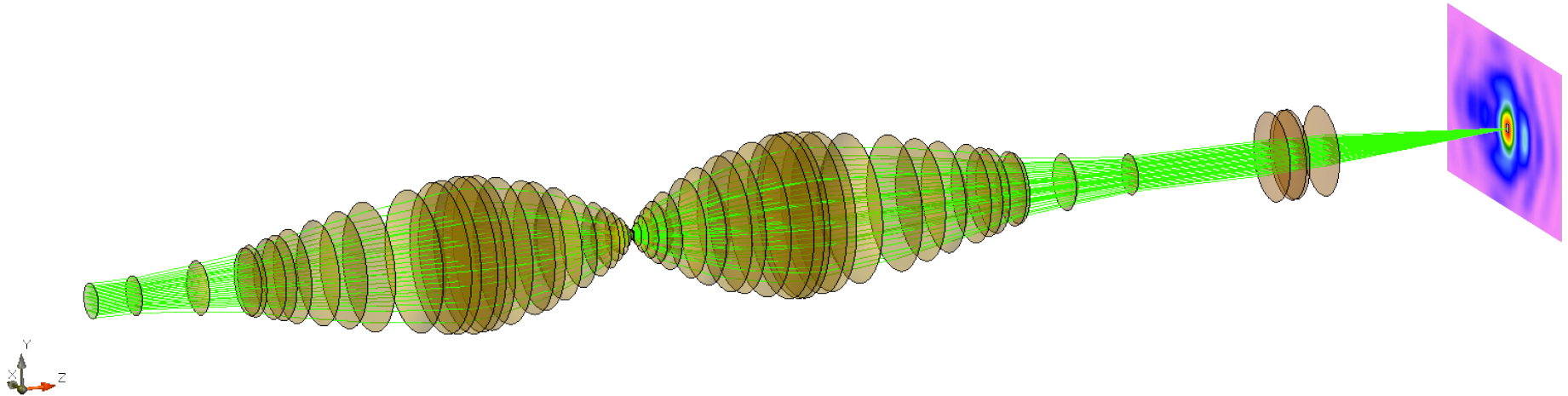
Optical Metrology > Microscopy

High NA Microscope Investigation of Different Samples

Task/System Illustration

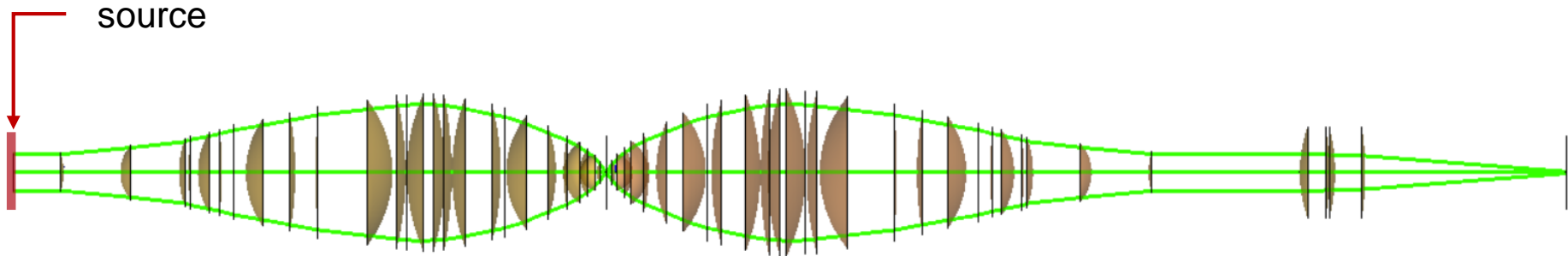


Highlights



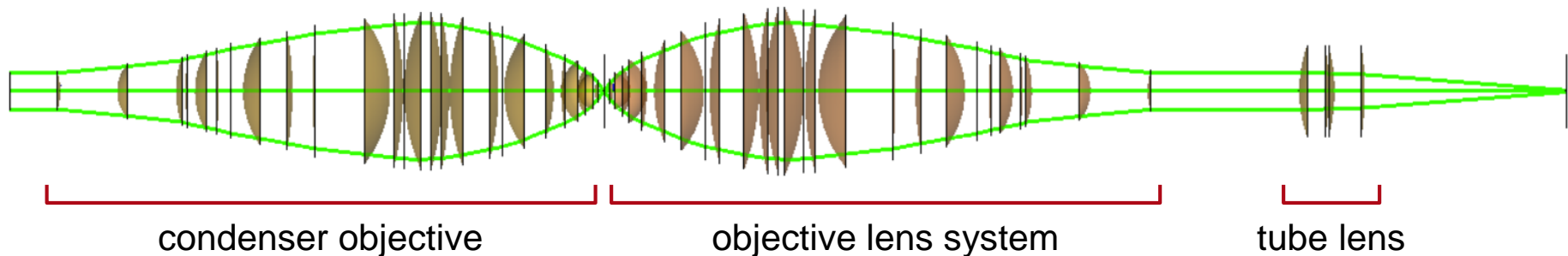
- full vectorial analysis of gratings within microscope systems
- fast high-performance analysis for complex systems within seconds
- simple switching between ray tracing and physical optics modeling

Specification: Light Source



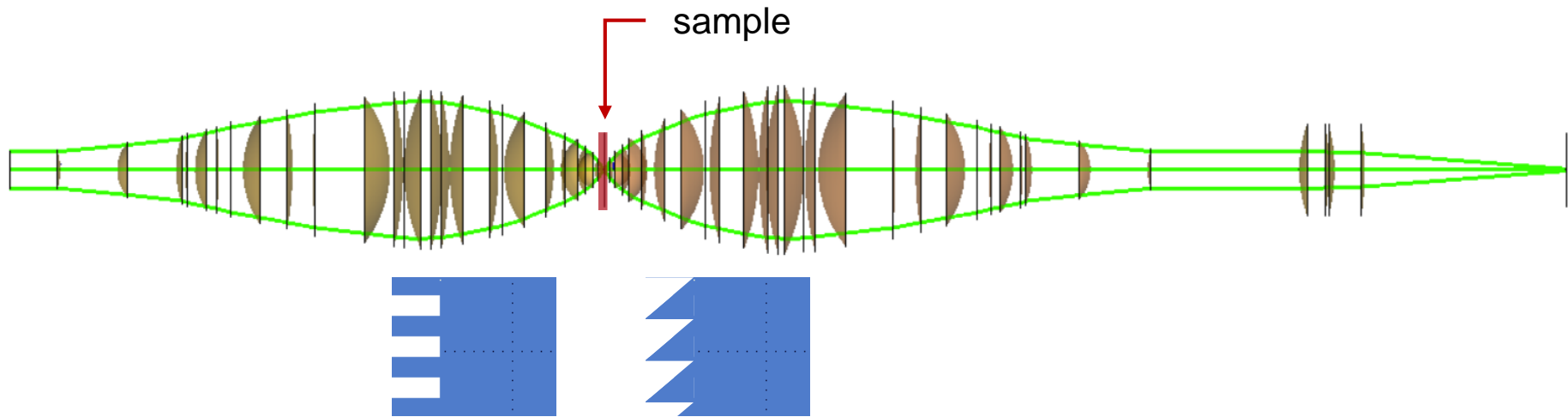
Parameter	Description / Value & Unit
type	plane wave
wavelength	532nm
polarization	linear in y-direction
diameter	3mm×3mm (round)

Specification: Lens Systems



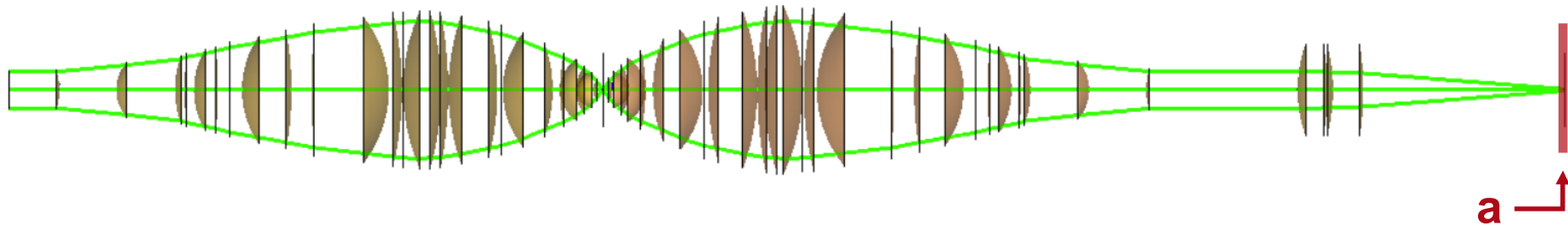
Components	Parameter	Description / Value & Unit
condenser objective	numerical aperture (NA)	0.76
	number of lenses	16
objective lens system	numerical aperture (NA)	0.76
	number of lenses	16
tube lens	numerical aperture (NA)	0.15
	number of lenses	2.2

Specification: Sample Structures



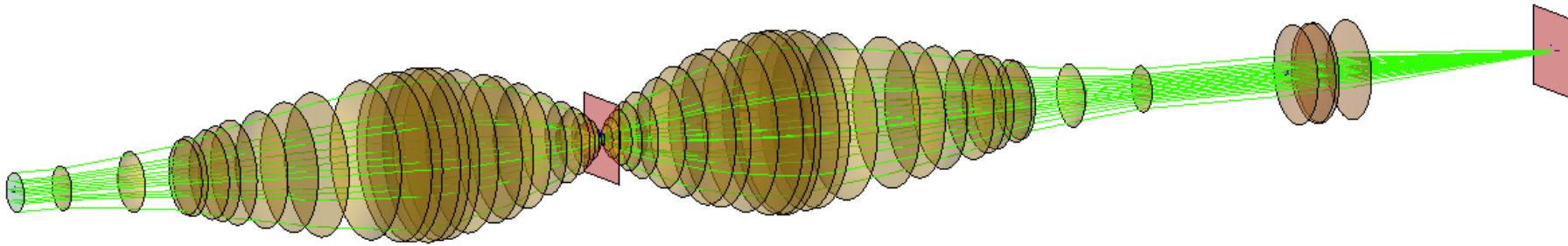
Parameter	Description / Value & Unit
type of grating profile	rectangular / sawtooth
grating period	450nm
duty cycle	0.5
grating height	610nm
grating material	fused silica

Specification: Detectors

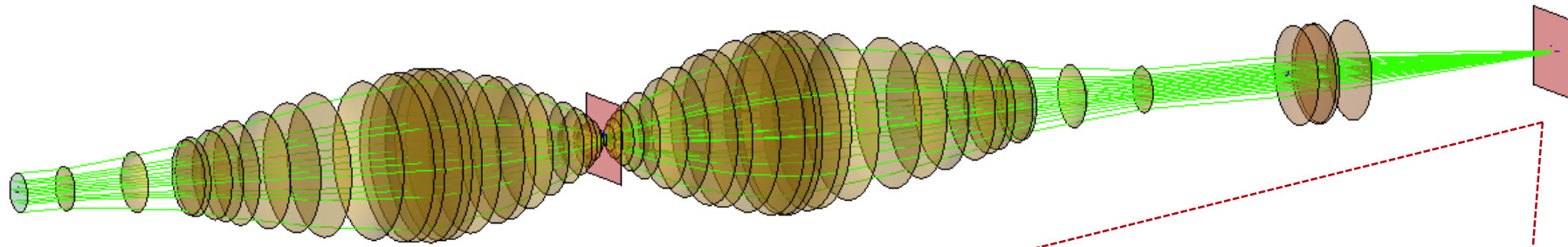


Position	Modeling Technique	Detector/Analyzer
full system	3D ray tracing	3D ray tracing system visualization
a	ray tracing	2D ray tracing dot diagram
	field tracing	2D field amplitude and intensity

Result: 3D Ray Tracing



Result: Field Tracing Rectangular Grating



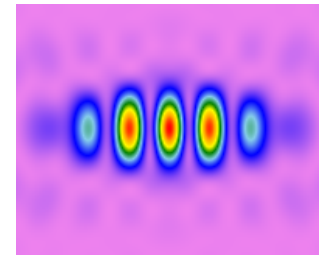
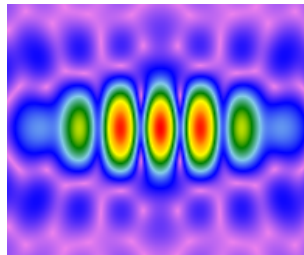
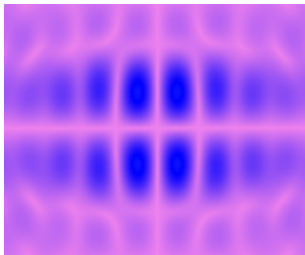
simulation time:
~6s

$|E_x|$

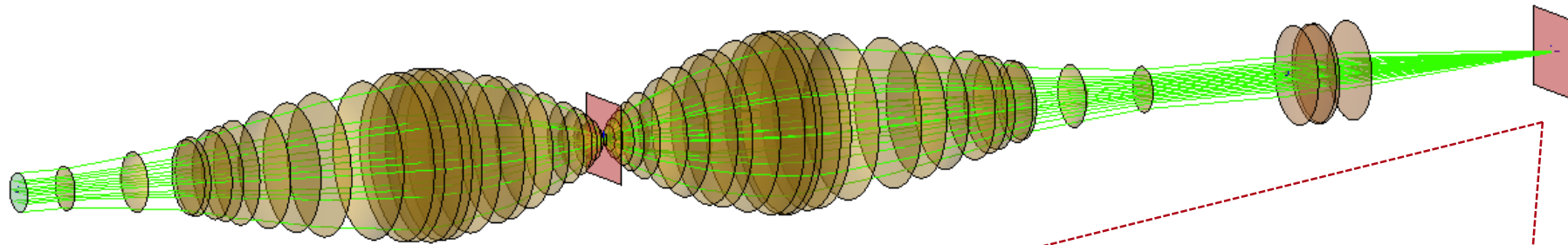
$|E_y|$

$|E_z|$

intensity



Result: Field Tracing Sawtooth Grating



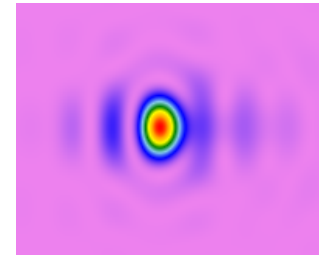
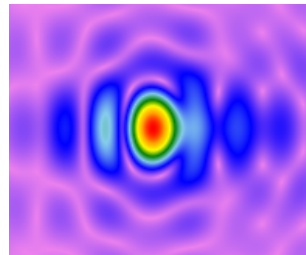
simulation time:
~7s

$|E_x|$

$|E_y|$

$|E_z|$

intensity



Document & Technical Info

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author	Rui Shi (LightTrans)
used VL version	7.0.0.29

Specifications of PC Used for Simulation

Processor	i7-4700MQ (4 CPU cores)
RAM	16 GB
Operating System	Windows 8